

# **ELEN E3106/4106 Lecture 10**

## **Metal-Semiconductor Junctions and Contacts**

### **Outline**

- Rectifying contacts
- Schottky barriers
- Schottky diodes
- Ohmic (non-rectifying) contacts

#### **Assignments:**

Reading: Streetman and Banerjee §5.7, C. Hu Ch. 4 Part III

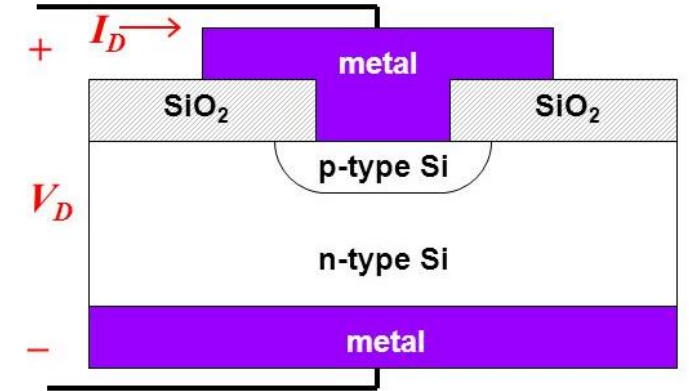
Homework 4 due Fri. Oct. 10<sup>th</sup> by 5pm

# Junction Recap

- Junction = boundary or interface between two types of materials.  
Examples:
- Diode = semiconductor \_\_\_\_\_ whose principle of operation is based on the junction!
  - The physical structure has other practical components
    - Like \_\_\_\_\_!
- Today we will be discussing another type of junction
  - Metal-semiconductor (\_\_\_\_)

**Physical structure:**  
(an example)

For simplicity, assume that the doping profile changes abruptly at the junction.



P-N junction

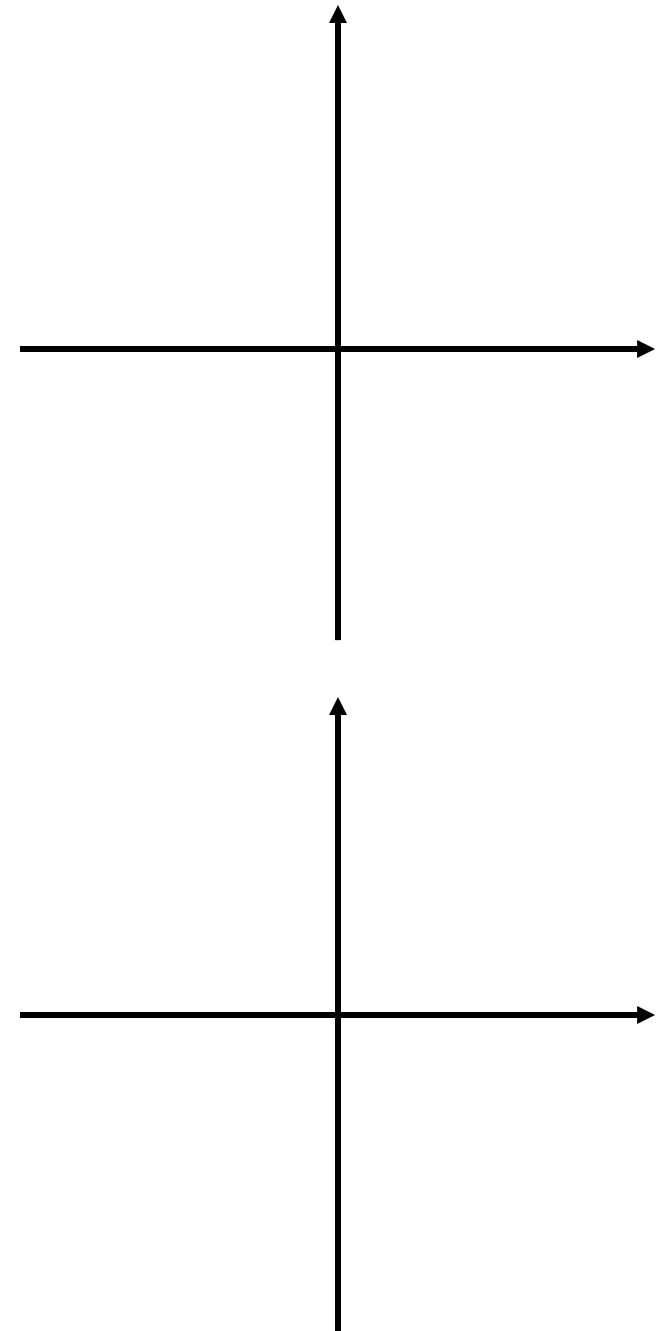


M-S junction



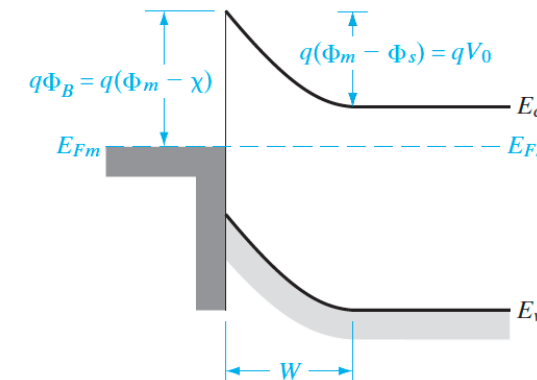
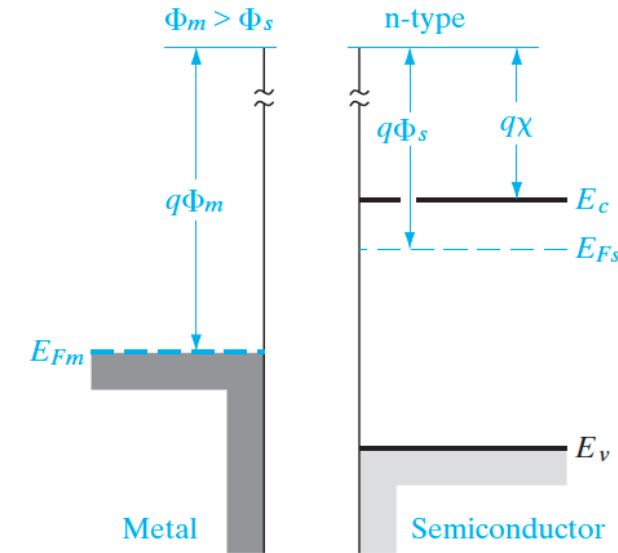
# M-S Junctions

- Crucial to the operation of most semiconductor devices
- When metal and semiconductor are joined, two types of contacts can result:
  1. Rectifying (\_\_\_\_\_)
  2. Non-rectifying (\_\_\_\_\_)
- Rectifying means that current can only pass in \_\_\_\_\_ direction
- Non-rectifying means current can pass in \_\_\_\_\_ directions
- Question: Is a p-n diode rectifying?



# Schottky Barrier Formation

- Recall: We discussed the metal work function \_\_\_\_\_
  - Energy needed to \_\_\_\_\_ an  $e^-$  from  $E_F$  to vacuum outside the metal
- The semiconductor also has a work function \_\_\_\_\_
- Metal and semi brought in contact--> \_\_\_\_\_ occurs
- Because we are in equilibrium, \_\_\_\_\_ must align
- Let's consider when  $\Phi_m > \Phi_s$  (n-type)
- Electrostatic potential of semiconductor must be raised (bands bend downward)

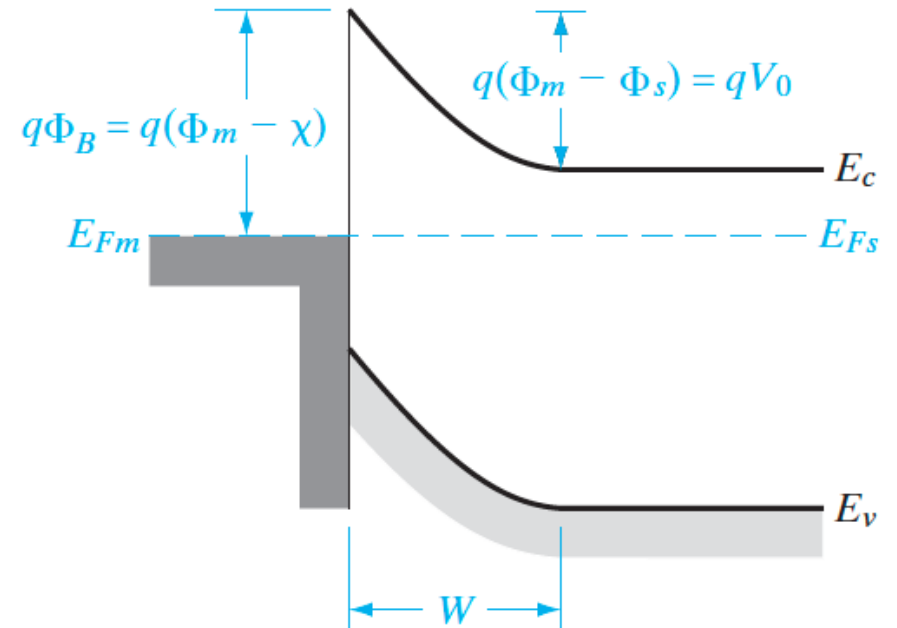
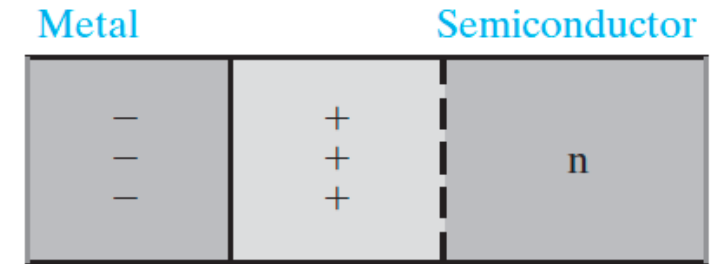


# Schottky Barrier Depletion Region

- Depletion region \_\_\_\_\_ will form
  - \_\_\_\_\_ charge from uncompensated donors  
\_\_\_\_\_ in semiconductor
  - \_\_\_\_\_ charge is on the metal
- Built-in contact potential \_\_\_\_\_ =  $\Phi_m - \Phi_s$
- The case is similar to  $p^+-n$  approximation
  - (-) charge on metal is a very thin sheet to the left of junction

$$= \left[ \frac{2\epsilon V_0}{q} \left( \frac{1}{N_a} + \frac{1}{N_d} \right) \right]^{1/2}$$

$$C = A \frac{\epsilon_s}{W_{\text{dep}}}$$



# Schottky Barrier Height

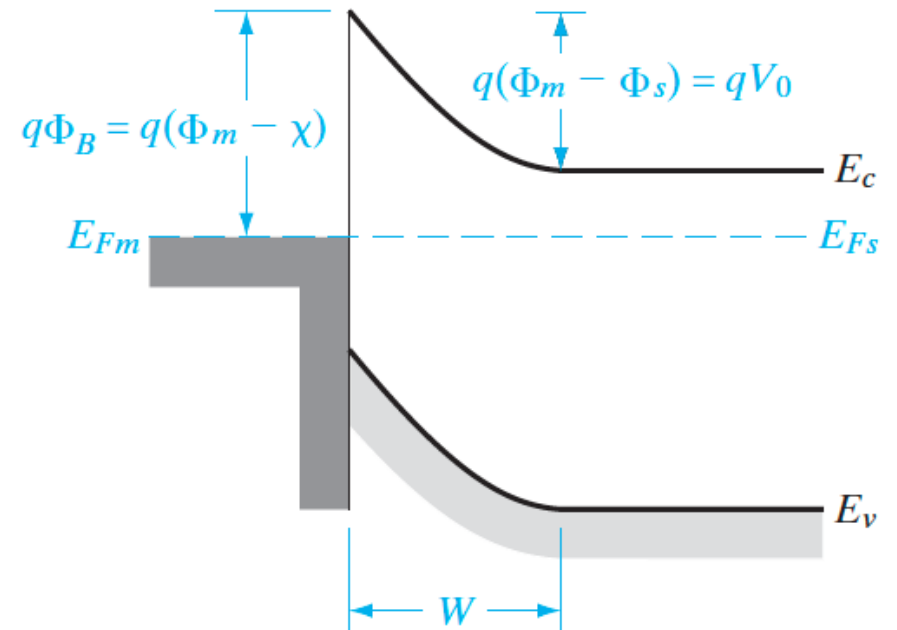
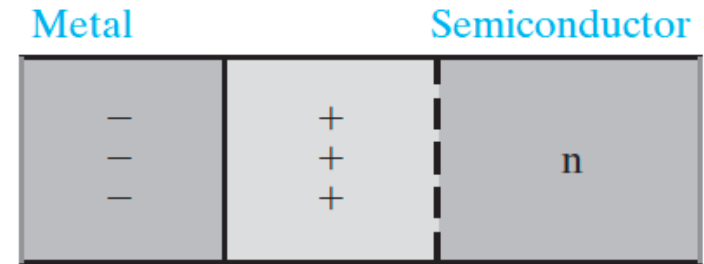
- An energy barrier exists at the metal-semiconductor interface
- Schottky barrier height is denoted

- $\Phi_B$  depends on:

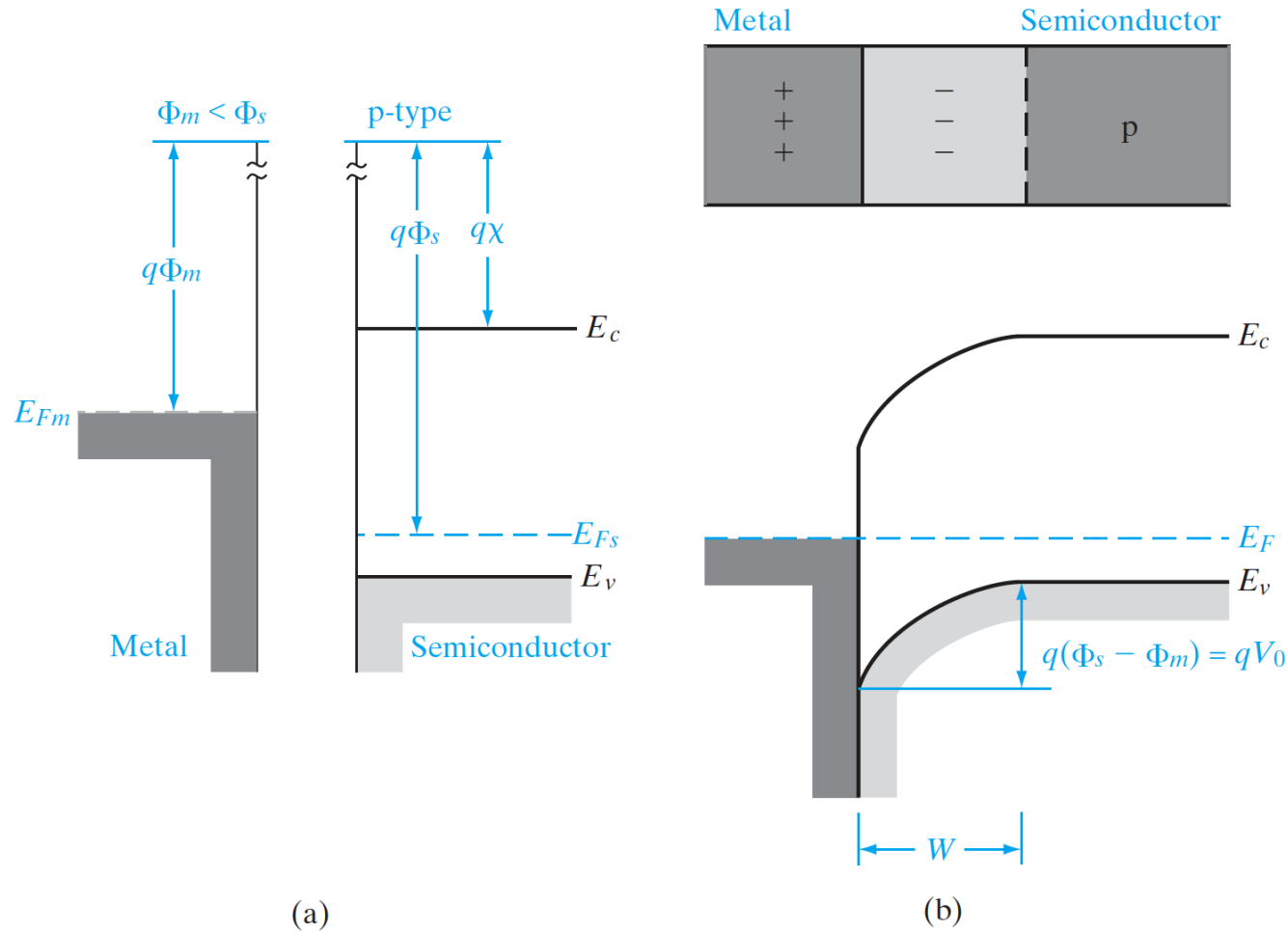
- \_\_\_\_\_
- \_\_\_\_\_

- The electron affinity, \_\_\_\_\_, is measured from the vacuum level to the semiconductor band edge

- $\Phi_B = \Phi_m - \chi$



# Schottky Barrier on p-type semiconductor

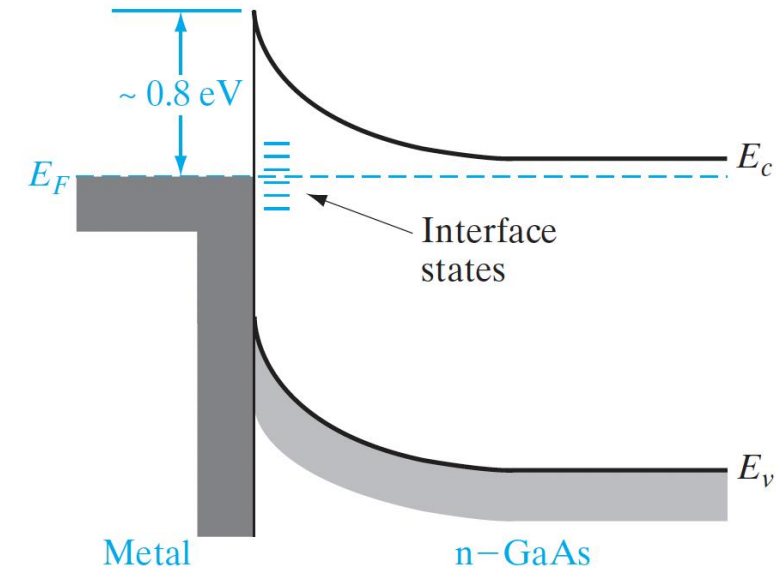


# Fermi Level Pinning

- Why does  $\Phi_B$  vary with the choice of the metal?
- Clear trend that  $\Phi_B$  increases with \_\_\_\_\_ metal work function
- We would expect 1 eV change in  $\Phi_m$  to result in \_\_\_\_\_ change in  $\Phi_B$ 
  - Quantitatively not true!
- So far our discussion has looked at *ideal* Schottky barrier behavior
- In reality, the M-S junction is not ideal
  - Surface states due to incomplete covalent bonds
  - Interface roughness
  - Thin interfacial layers
- These can pin the Fermi level at a certain position regardless of metal work function

TABLE 4–4 Measured Schottky barrier heights for electrons on N-type silicon ( $\phi_{Bn}$ ) and for holes on P-type silicon ( $\phi_{Bp}$ ). (From [7].)

Metal	Mg	Ti	Cr	W	Mo	Pd	Au	Pt
$\phi_{Bn}$ (V)	0.4	0.5	0.61	0.67	0.68	0.77	0.8	0.9
$\phi_{Bp}$ (V)		0.61	0.50		0.42		0.3	
Work Function $\psi_M$ (V)	3.7	4.3	4.5	4.6	4.6	5.1	5.1	5.7



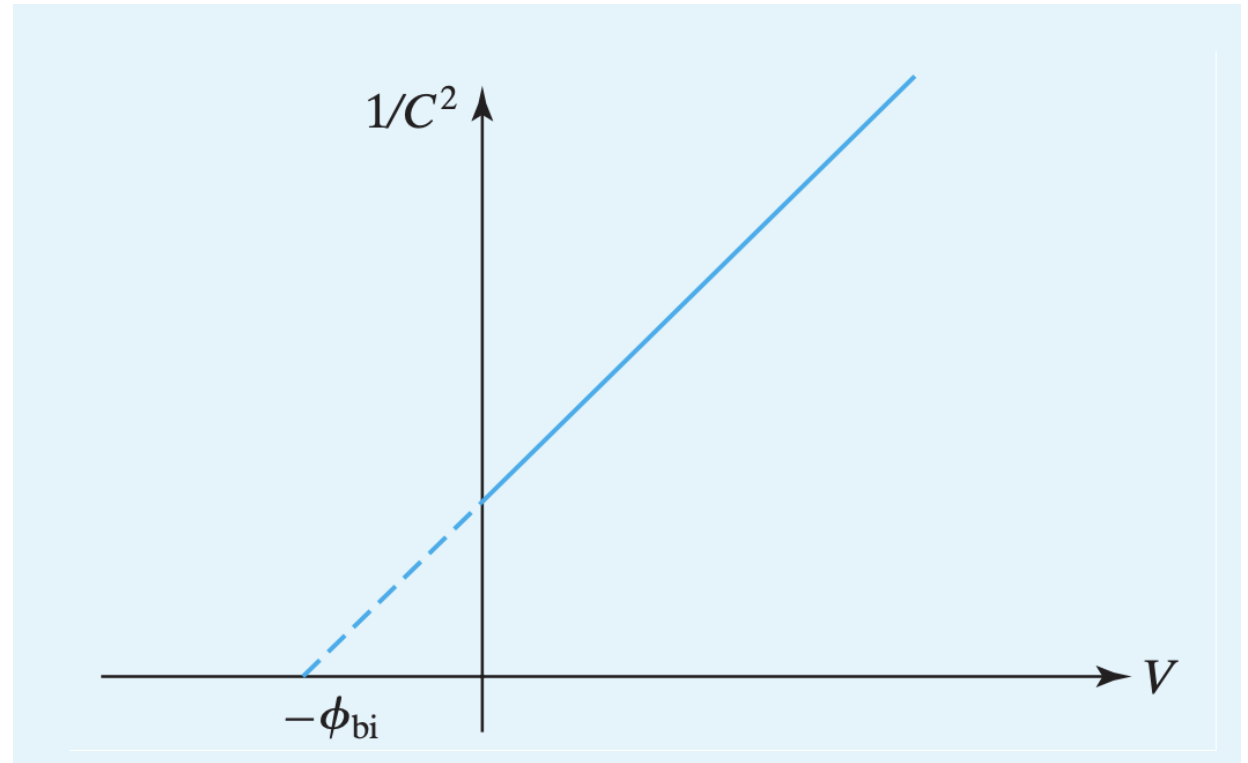


# Using C-V Data to Determine Schottky Barrier Height

$$C = A \frac{\epsilon_s}{W_{\text{dep}}}$$
$$\frac{1}{C^2} = \frac{2(\phi_{bi} + V)}{qN_d\epsilon_s A^2}$$

$$W_{\text{dep}} = \sqrt{\frac{2\epsilon_s(\phi_{bi} + V)}{qN_d}}$$

$$q\phi_{bi} = q\phi_{Bn} - (E_c - E_F) = q\phi_{Bn} - kT \ln \frac{N_c}{N_d}$$

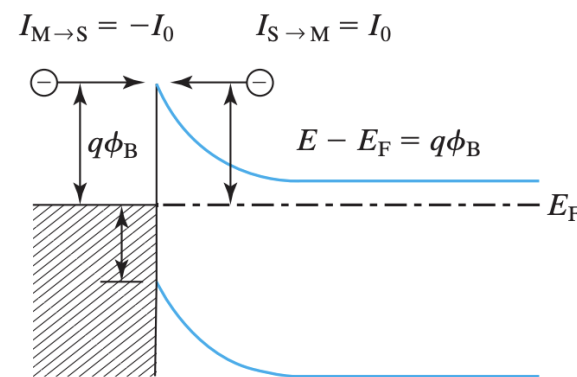


# Explanation of Rectifying I-V Characteristics

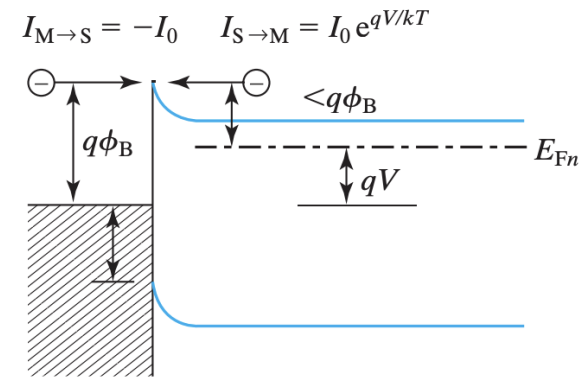
- Rectifying, with easy current flow in the forward direction and little current in the reverse direction

$$I = I_0(e^{qV/kT} - 1)$$

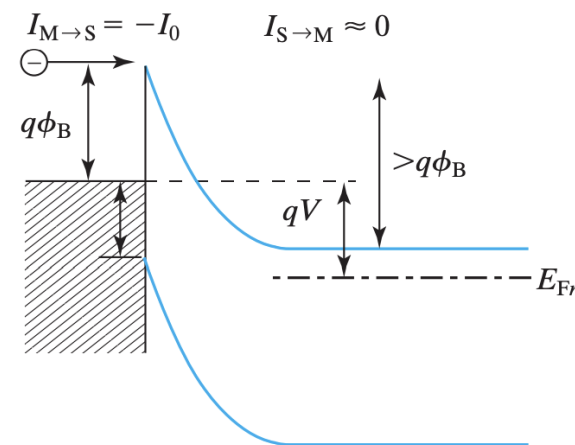
- Forward current due to injection of \_\_\_\_\_ carriers
- Left-traveling  $e^-$  have a thermal velocity
  - Thermionic emission theory



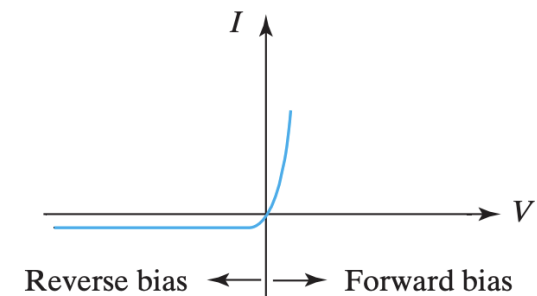
(a)  $V = 0$ .  $I_{S \rightarrow M} = |I_{M \rightarrow S}| = I_0$



(b) Forward bias. Metal is positive wrt Si.  $I_{S \rightarrow M} \gg |I_{M \rightarrow S}| = I_0$



(c) Reverse bias. Metal is negative wrt Si.  $I_{S \rightarrow M} \ll |I_{M \rightarrow S}| = I_0$



(d) Schottky diode  $I$ - $V$ .

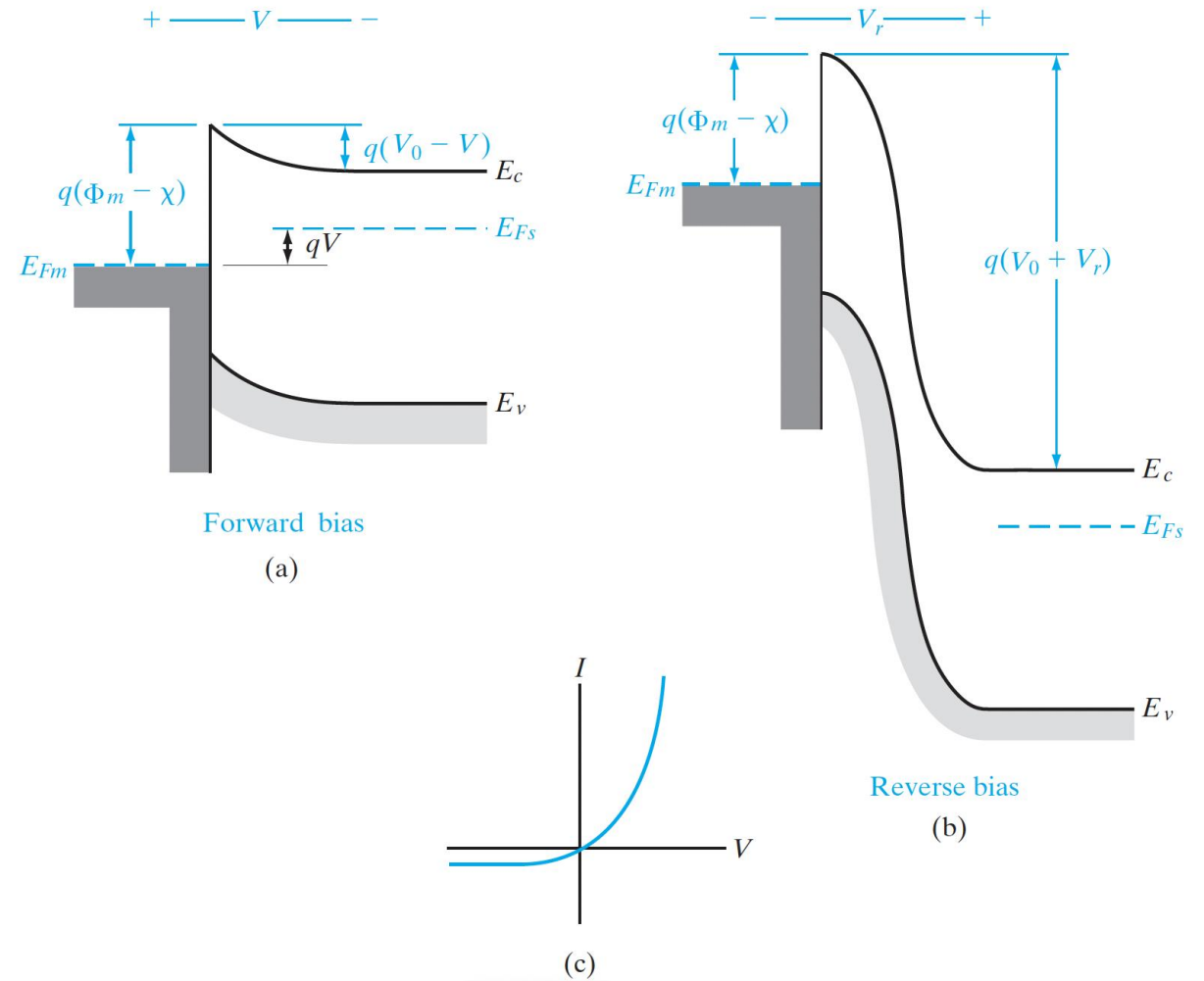
# Reverse Saturation Current

- Reverse saturation current is \_\_\_\_\_
- Not as simply derived as in p-n diode, but what does it depend on?
- Is it affected by the bias voltage?

$$I_0 \propto e^{-q\Phi_B/kT}$$

$$I_0 = AKT^2 e^{-q\phi_B/kT}$$

- Richardson constant:  $K = \frac{4\pi q m_n k^2}{h^3}$
- Units: \_\_\_\_\_



# Schottky Diode Equations

- Desired: \_\_\_\_ barrier height, low \_\_\_\_\_ (leakage current)
- Ideal diode equation:

$$I = I_0(e^{qV/kT} - 1)$$

- Taking into account non-idealities, forward current is:

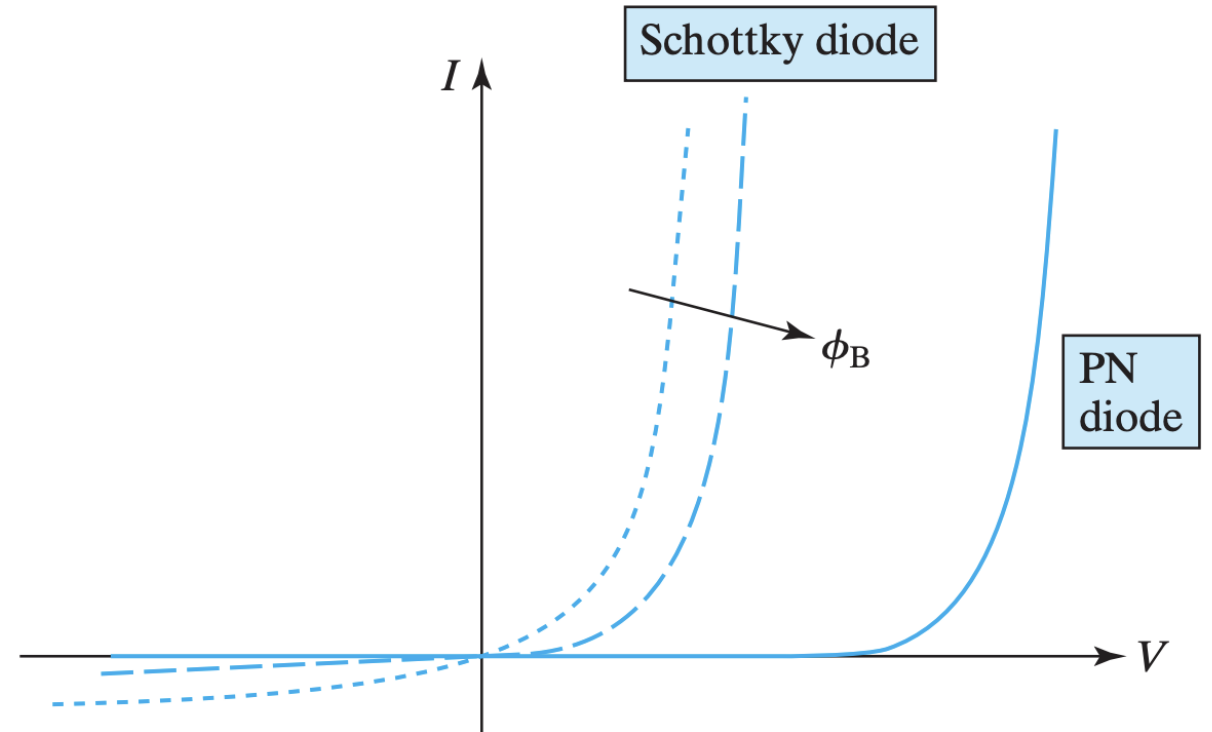
$$I = ABT^2 e^{-q\Phi_B/kT} e^{qV/nkT}$$

- Ideality factor \_\_\_\_ varies from 1-2 like p-n junction, but arises for different reasons

# Schottky Diode Applications

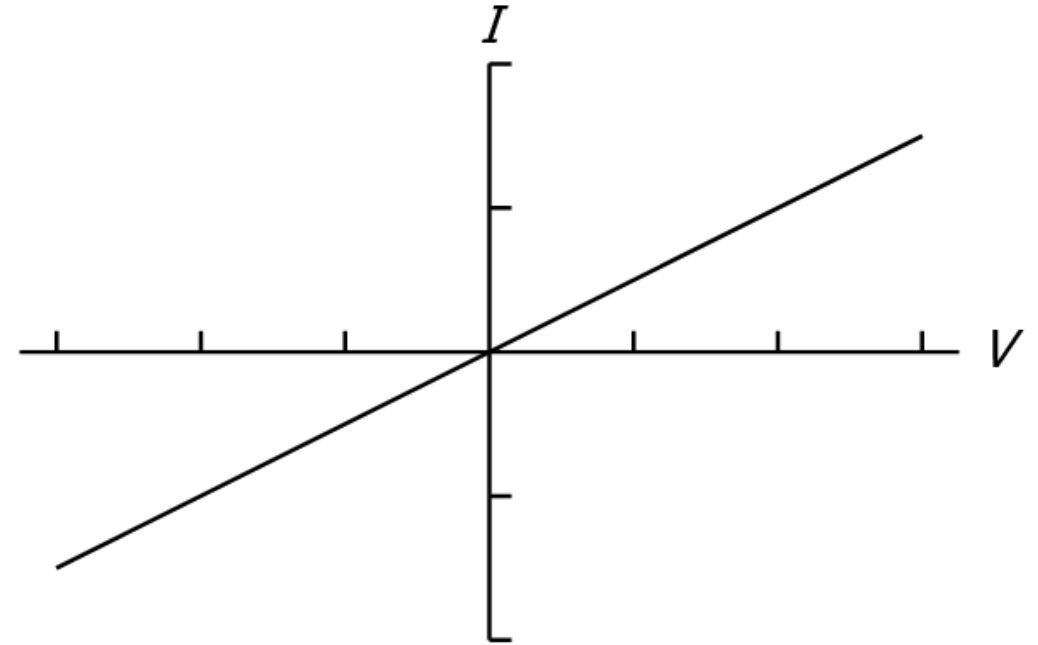
- Advantages over p-n diode:
  - High-frequency properties and switching speed are generally better
  - Simpler fabrication process
  - $I_0$  of a Schottky diode can be  $10^3$ – $10^8$  times larger
    - Preferred in low-voltage and high-current applications
- Are there downsides to larger  $I_0$ ?

$$I = I_0(e^{qV/kT} - 1)$$



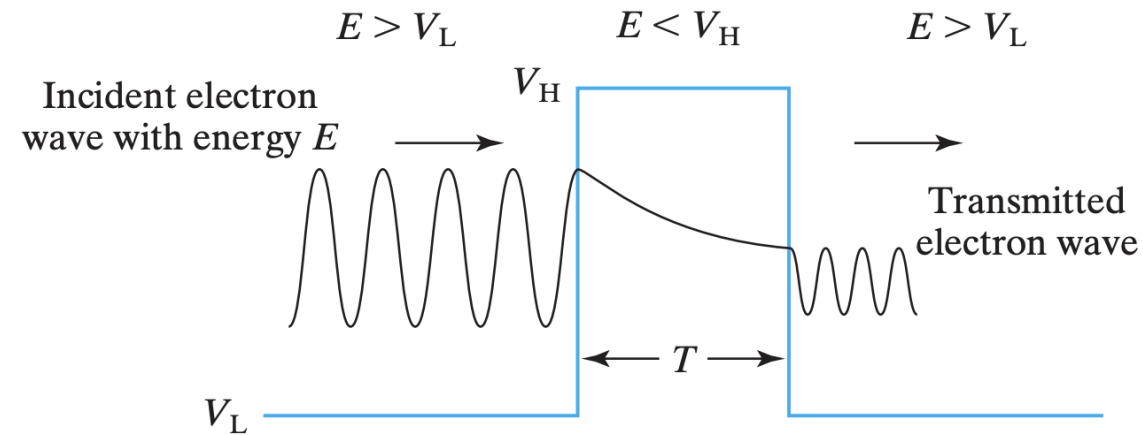
# Non-Rectifying (Ohmic) Contacts

- M-S contacts are ohmic when we have linear I–V characteristic in both biasing directions
- What are the applications?
  - Contacting and interconnecting different regions of devices
- Desired properties of ohmic contacts:
  - \_\_\_\_\_
  - \_\_\_\_\_
- 2 methods to formation:
- 1) Low barrier height
- 2) Heavily \_\_\_\_\_ the semiconductor!
  - More practical!



# Quantum Mechanical Tunneling

- *There is a finite probability for  $e^-$  to tunnel through a potential barrier!*
- Even if  $e^-$  doesn't have enough \_\_\_\_\_
- $e^-$  with energy  $E$  arriving at barrier with high  $V_H$
- Traveling wave decays
- Emerges from barrier with reduced \_\_\_\_\_
- Tunneling probability increases \_\_\_\_\_ with decreasing barrier thickness



$$P \approx \exp\left(-2T \sqrt{\frac{8\pi^2 m}{h^2} (V_H - E)}\right)$$

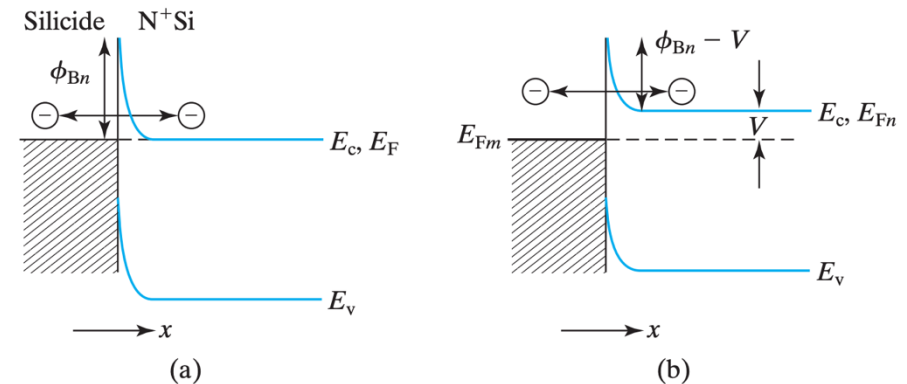
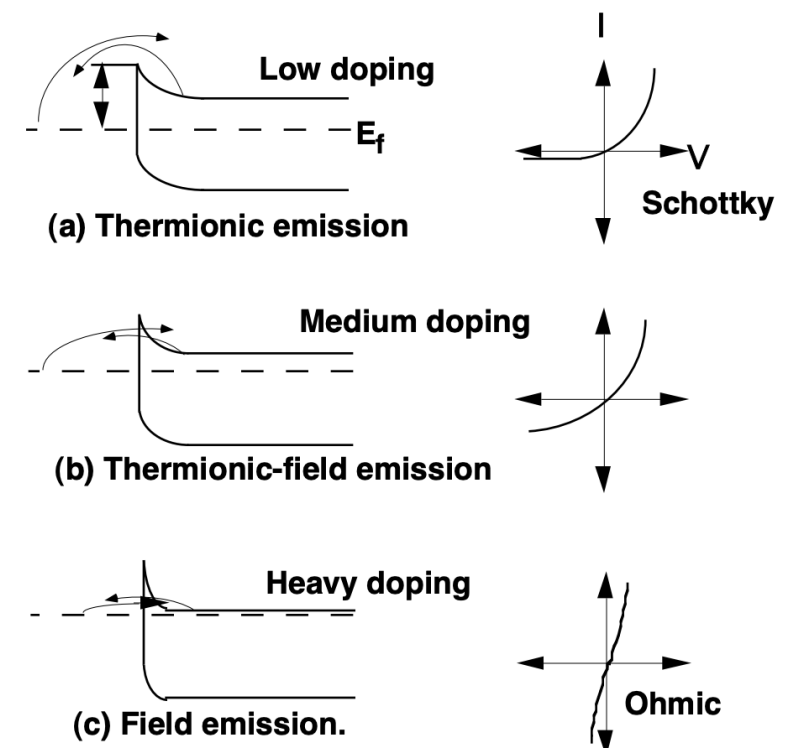
# Heavily Doped Ohmic Contacts

- With high dopant concentrations, barrier becomes thin

$$T \approx W_{\text{dep}}/2 = \sqrt{\epsilon_s \phi_{Bn} / (2qN_d)}$$

- High probability e- can pass through the barrier by tunneling
- Typical depletion layer width \_\_\_\_\_ of heavily doped Si?

- Tunneling probability largely independent applied bias
  - Constant resistance (ohmic) contact

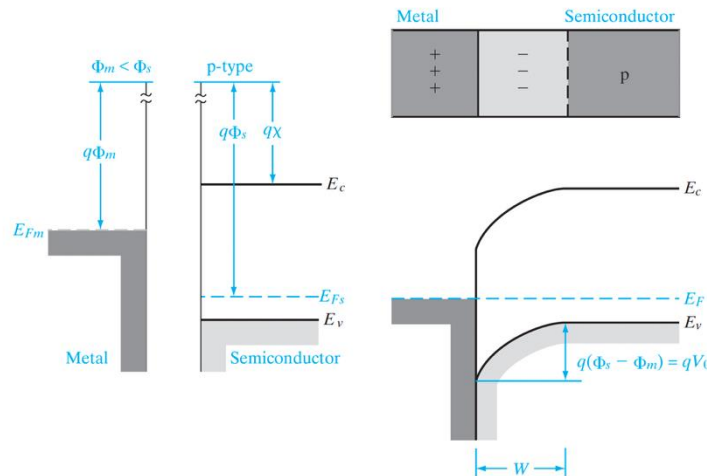


**FIGURE 4-44** (a) Energy band diagram of metal-N<sup>+</sup>Si contact with no voltage applied and (b) the same contact with a voltage,  $V$ , applied to the contact.



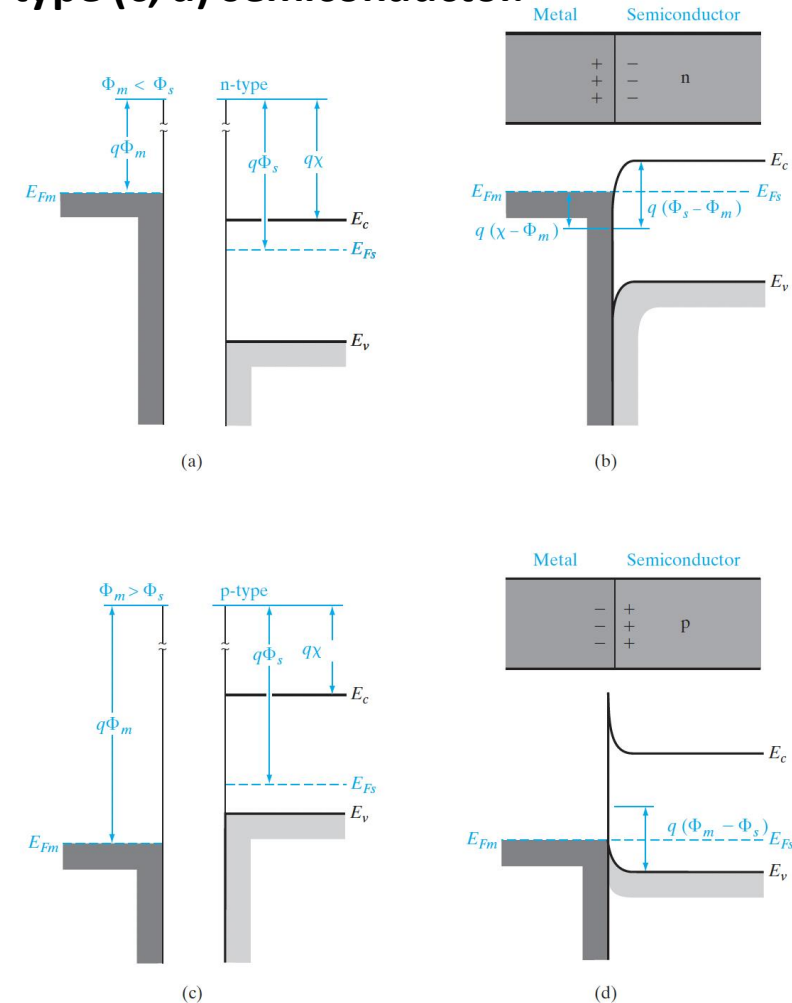
# Summary of Schottky and ohmic contacts (low barrier height, method of formation #1):

- Metal/n-type semiconductor:
  - Schottky:  $\Phi_s < \Phi_M$
  - Ohmic:  $\Phi_M < \Phi_s$
- Metal/p-type semiconductor:
  - Schottky:  $\Phi_s > \Phi_M$
  - Ohmic:  $\Phi_M > \Phi_s$



**Schottky barrier on p-type semiconductor and a metal with a smaller work function.**

Ohmic contacts on n-type (a, b) and p-type (c, d) semiconductor.



## How do we find semiconductor work function?

- $\Phi_s$  : Work function of the semiconductor =  $E_{vac} - E_F$
- $\chi$ : Electron affinity of the semiconductor =  $E_{vac} - E_C$
- Looking at a band diagram, this means we can find  $\Phi_s$  if we are given  $\chi$  and the

- n-type semiconductor example:

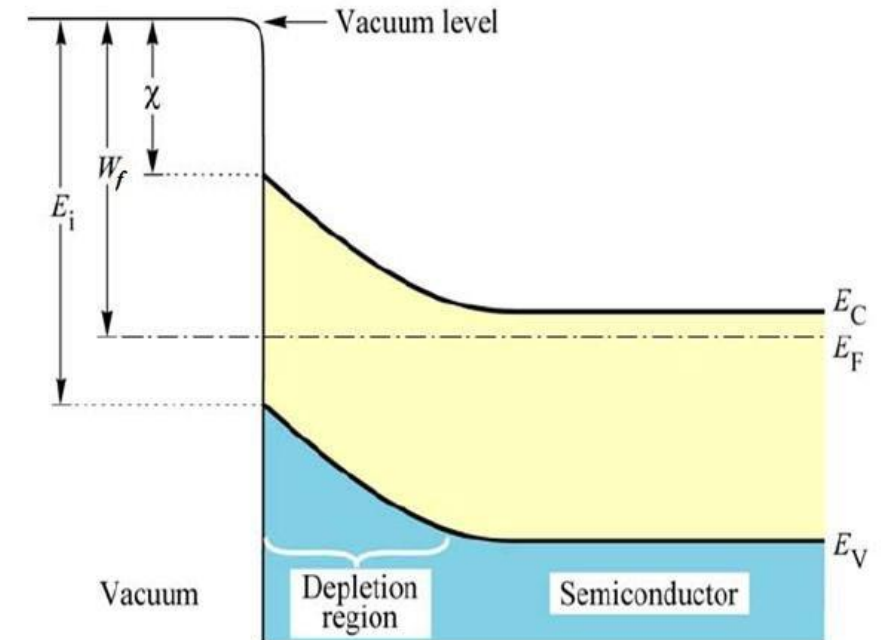
- $\Phi_s = (E_{vac} - E_C) + (E_C - E_F)$
- $\Phi_s = (E_{vac} - E_C) + (E_C - E_i) - (E_F - E_i)$
- $\Phi_s = \chi + \frac{E_g}{2} - (E_F - E_i)$

- Recall: Equilibrium carrier concentrations ( $cm^{-3}$ ):

- $n_0 = n_i e^{(E_F - E_i)/kT}$ ,  $p_0 = n_i e^{(E_i - E_F)/kT}$

$$\Phi_s = \chi + \frac{E_g}{2} - kT \ln \left( \frac{n_0}{n_i} \right)$$

(n-type)



# Contact Resistance

- Desired: low contact resistance
- An important property of contacts is the specific contact resistance,  $R_c$ 
  - Units:
- A measure of how easily current flows through a contact
- For an n-type semiconductor:

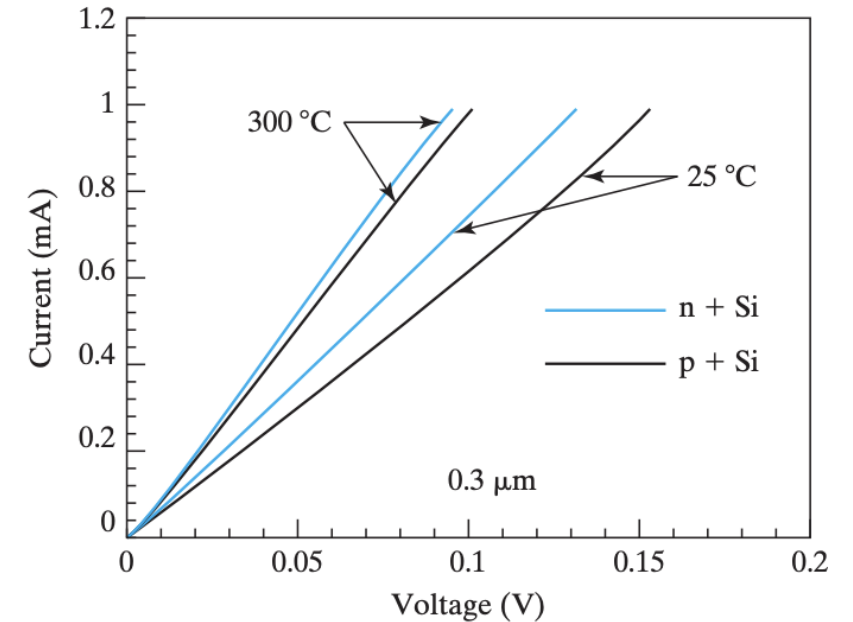
$$R_c \equiv \frac{V}{J} = \frac{2 \cdot e^{H\phi_{Bn}/\sqrt{N_d}}}{qv_{thx}H\sqrt{N_d}}$$

$$\propto e^{H\phi_{Bn}/\sqrt{N_d}}$$

$$v_{thx} = -\sqrt{2kT/\pi m_n}$$

$$H \equiv \frac{4\pi}{h} \sqrt{(\epsilon_s m_n)/q}$$

- Recall, \_\_\_\_\_ is the thermal velocity
- Same thing true for p-type, but we replace  $N_d, \Phi_{Bn}, m_n$  by  $N_a, \Phi_{Bp}, m_p$



**I-V characteristics of a 0.3 micron diameter TiS<sub>2</sub> contact on n+ and p+ Si.**